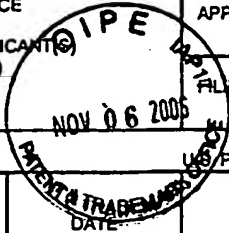


FORM PTO 1449 (modified) IDS - 11/06/2006 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY DOCKET NO. 03500.017988.		APPLICATION NO. 10/551,112		
LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary)			APPLICANT Susumu Yasuda, et al.				
			FILING DATE September 28, 2005		GROUP 2858		
US PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
WB		2003/0057977	03/2003	Werner, Jr. et al.	324	754	
WB		2006/0171728	08/2006	Ichimura et al.	399	48	
WB		2006/0186898	08/2006	Ichimura et al.	324	663	
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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
WB		1 003 044 A2	05/2000	Europe			
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WB		Riehl, P. S., "Microsystems for Electrostatic Sensing", Dissertation, Nov. 2002, pp. 1-8, 32-40, 79-84.					
WB		Hsu, C. H. et al., "Micromechanical Electrostatic Voltmeter", Proc. Int'l. Conf. on Solid State Sensors and Actuators, NY, IEEE, US, vol. Conf. 6, 24, June 1991, pp. 659-662					
EXAMINER				DATE CONSIDERED			
/Walter Benson/				01/07/2007			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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